

ABSTRACT

Described are a method and a measuring device for measuring the impedance in a fluidic microsystem comprising a compartment (10) through which a liquid comprising at least one suspended particle (16) flows, and in which at least one impedance detector (40) is arranged, by means of which for detection of the at least one particle at least one impedance value is acquired which is characteristic for the impedance of the compartment, and which in the presence of the at least one particle changes in a predetermined way, wherein focusing of the at least one particle takes place in a predetermined space relative to the impedance detector, wherein focusing involves a movement of the at least one particle relative to the fluid flowing in the compartment as a result of dielectrophoretic forces, which forces are exerted by means of at least two focusing electrodes (30).

Fig. 1